

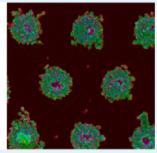
Selective Hydrothermal Method To Create Patterned and Photoelectrochemically Effective Pt/WO3 Interfaces

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ABSTRACT: A hydrothermal method based on the use of hydrogen peroxide is described to grow a homogeneous layer of tungsten oxide (WO₃) on a platinum (Pt) film supported on a silicon wafer. WO3 growth is highly selective for Pt when present on silicon in a patterned arrangement, demonstrating that Pt catalyzes decomposition of the WO₃ precursor in solution. The obtained Pt/WO3 interface yields high photocurrents of 1.1 mA/cm² in photoelectrochemical water splitting when illuminated by a solar simulator. The photocurrents are significantly higher than most previously reported values for hydrothermally grown layers on indium-tin oxide





and fluorine-tin oxide glasses. The selective growth method thus provides new options to effectively implement WO3 in photoelectrochemical devices.

KEYWORDS: tungsten oxide, platinum, hydrothermal synthesis, patterning, photocatalysis

■ INTRODUCTION

Tungsten oxide (WO₃) is one of the most frequently studied binary oxides in photoelectrochemical cells, functioning as a photoanode.1 Furthermore, photocatalytic application of WO₃ ranges from water purification (dye degradation) to visiblelight-induced splitting of water into hydrogen and oxygen. In the latter application, WO3 shows high water oxidation efficiency in the presence of other specific semiconducting oxides, such as modified SrTiO3, thus creating a so-called Zscheme configuration.² Particles and supported layers of WO₃ can be grown in various morphologies and crystal composition by several synthesis methods.^{3–7} In particular, hydrothermal growth has led to compositions effective in the abovementioned applications.^{8,9} A method employing hydrogen peroxide (H₂O₂) has recently been demonstrated to yield WO₃ particles with well-defined morphologies, without the need for structure-directing additives. 10,11 When a seed layer was used, homogeneous WO3 layers were successfully grown on indiumtin oxide (ITO)-coated glass substrates. 12,1

Growth of WO₃ on metal surfaces has not been extensively studied, while having control over the growth of well-defined WO₃ layers on (patterned) metal surfaces is highly relevant for the creation of new device concepts in photoelectrochemistry. We hypothesize a favorable electron transfer from photoexcited WO₃ to a metal, and in particular platinum (Pt), based on the frequently reported positive effect of Pt nanoparticles on the photocatalytic performance of WO₃. This is typically assigned to electron scavenging by the Pt nanoparticles, enhancing the lifetime of excited states. ^{14,15} Furthermore, Nozik et al. propose the use of inequality of work functions to create an electron flow from the semiconductor to metal, 16 on which basis a

photoelectrochemical diode was constructed and shown to be effective in water splitting.1

The objective of this study is to demonstrate the controlled growth of WO3 on a silicon (Si)-supported Pt thin film. We modified the hydrothermal process described by others, 12,13 to obtain well-defined WO3 layers without the need of a seeding layer. We confirm a catalytic effect of Pt in the formation of the WO₃ layers by demonstrating the growth to be selective on Pt when present on Si in a patterned arrangement. Finally, we demonstrate excellent efficiency of the Pt/WO₃ composition in photoelectrochemical applications.

EXPERIMENTAL SECTION

A 100-nm-thick Pt film was sputtered on an oxidized (100) Si wafer. To allow strong adhesion, a 13 nm titanium (Ti) layer was used between the substrate and film. Sputtering was performed using inhouse-developed sputtering equipment, applying a 6.6 mbar argon atmosphere. For Pt and Ti, 2 in. targets were used and a 200 W directcurrent sputter was applied.

A dot pattern was defined in the Ti/Pt film using photolithography and passive ion beam etching with Ar+ ions in an Oxford Ionfab 300 reactive ion beam etching system.

WO3 layers were grown hydrothermally on the Pt surface, without the need of a seeding layer. H₂WO₄ (Sigma Aldrich) was dissolved in 35% H₂O₂ (Sigma Aldrich) to a concentration of 0.5 M at 80 °C under vigorous stirring. After cooling to room temperature, this solution was diluted to 0.01 M H₂WO₄ by the addition of distilled water. Two slightly different procedures for growth were followed. In the first procedure, 20 mL of the 0.01 M solution was transferred directly after into a Teflon beaker and inserted in a stainless steel autoclave [a 4748

Received: September 12, 2013 Accepted: November 20, 2013 Published: November 20, 2013

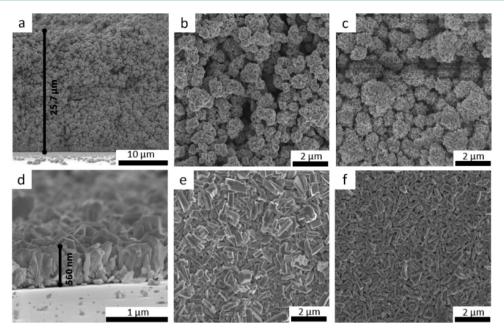


Figure 1. SEM images of hydrothermally grown WO₃ layers: (a and b) side and top views of flower-type layers formed in the presence of excess H_2O_2 ; (c) top view of the layer after subsequent annealing at 600 °C; (d and e) side and top views of an as-prepared rod-type layer in lower concentrations of H_2O_2 , induced by decomposition of excess H_2O_2 prior to hydrothermal treatment; (f) top view of the layer after subsequent annealing at 600 °C.

acid digestion vessel (Parr Instruments)]. This was followed by immersion of the Si/SiO₂/Ti/Pt substrate, closure of the autoclave, and hydrothermal treatment at 170 °C for 18 h, applying a heating rate of 10 °C/min. In the second procedure, the 0.01 M solution was pretreated overnight at room temperature by two small pieces of the Si/SiO₂/Ti/Pt substrate with a total area of approximately 1 cm². Oxygen evolution due to decomposition of the excess of H2O2 was initially clearly visible. The gas evolution stopped after overnight treatment. The pieces were removed, and synthesis was continued in hydrothermal conditions as described for the first procedure by adding the solution and Si/SiO₂/Ti/Pt substrate to the Teflon beaker. For both procedures, after the digestion vessel was cooled to room temperature by a natural cool down, the substrates were removed from the solution, carefully rinsed with distilled water, and dried under a mild nitrogen flow. Finally, the samples were annealed at 600 °C for 12 h in static air, applying a heating rate of 10 °C.

Characterization of the grown layers was performed by high-resolution scanning electron microscopy (HR-SEM) and X-ray diffraction (XRD) analysis. For imaging, a Nova 600-nanolab HR-SEM instrument (FEI Instruments) was used, and for combined imaging/elemental mapping, a Merlin HR-SEM (Metrology Zeiss) system, equipped with an energy-dispersive X-ray spectroscopy (EDX) instrument, was used. A Bruker D2 powder diffractometer (equipped with a Cu K α source) was used for analysis of the WO $_3$ crystal structure.

Electrochemical measurements were performed in a three-electrode cell setup equipped with a Versastat 4 potentiostat (Princeton). A 1.5AM solar simulator (model 10500, ABET Technologies) was applied as the light source. The reactor consisted of a 25 mL optical glass cuvette, which filtered most of the emitted UV light. The counter electrode (EC) consisted of a Pt mesh connected to a Pt wire. A 3.0 M Ag/AgCl reference electrode (BASi) was used, with a potential of +0.210 V vs. NHE. This value can be converted to $V_{\rm RHE}$ by the Nernst equation:

$$V_{\text{RHE}} = V_{\text{Ag/AgCl}} + V_{\text{Ag/AgCl} \text{ vs RHE}} + 0.059 \text{pH}$$
 (1)

Contact to the Si-supported Pt/WO_3 working electrode was accomplished by a stainless steel clamp, protected from the electrolyte by encapsulation in an epoxy resin. The WO_3 layer was faced toward the light source. The electrolyte consisted of a $0.3M\ H_3PO_4$ solution.

RESULTS AND DISCUSSION

The morphology of the WO_3 layers hydrothermally grown on Pt in the presence of H_2O_2 can be composed of two different morphologies; see Figure 1. WO_3 grown in the presence of an excess of H_2O_2 shows a flower-like morphology (Figure 1a,b) and a high porosity. Cross-sectional views indicate a thickness of this porous layer of around 25 μ m. When the excess of H_2O_2 in the precursor solution was allowed to decompose prior to hydrothermal WO_3 growth, a dense layer with crystals in a rod-like morphology is obtained (Figure 1d,e). Side-view measurements show a thickness of 560 nm. This thickness is rather independent of the time of hydrothermal treatment because a large fraction of WO_3 crystallizes in solution. After annealing at 600 °C (Figure 1c,f), the layers hardly change their morphology; only some facets appear to become more rounded.

Besides the large differences in the thickness and morphology, a large difference in adhesion of the WO₃ layer to the Pt film was observed for the two different hydrothermal procedures. The rod-shaped crystals showed strong adhesion upon rinsing and drying procedures, while the thick and porous flower-like layers were substantially washed off when exposed to the same procedure. These characterization results demonstrate the large effect of the absence or presence of an excess of $\rm H_2O_2$ on the surface morphology. Although we did not investigate this aspect, Jiao et al. ¹² attributed the morphology differences to the absence or presence of a WO₃ seeding layer on their applied fluorine-doped tin oxide (FTO)-coated glass. With a (spin-coated) WO₃ seeding layer, a rod-like morphology was obtained, whereas without the seeding layer, WO₃ crystals with high porosity and flower-like shape were formed.

XRD was applied to characterize the crystal phase of the grown layers; see Figure 2. The diffraction lines of Pt and Si of the substrates are visible at 40.0 and 47.4°. The WO₃ crystals of both layer morphologies consist of WO₃·0.33H₂O (JCPDS 87-

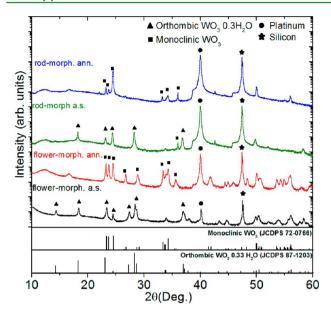


Figure 2. XRD patterns of the WO₃ layers with rod- and flower-type morphologies before and after annealing at 600 °C. As synthesized, both morphologies exhibit a tungsten oxide hydrate phase. By annealing, this hydrate phase is converted to the monoclinic tungsten oxide phase.

1203), with the main diffraction lines at 14.3 and 18.2°, as well as two additional characteristic lines around 23.4 and 24.2°. After annealing at 600 °C, the monoclinic WO₃ phase is formed (JCDPS 72-0766) with three main characteristic diffraction lines at 23.2, 23.7, and 24.4°, which are representative of the [200], [020], and [002] crystal planes, respectively. In the case of the rod-like morphology, there seems to be a preferential orientation in the [002] direction of the crystal, while in the case of the flower-like morphology, the distribution for the [200], [020], and [002] planes is approximately equal.

The following two reactions are proposed to describe the process of WO₃ formation: 12

$$H_2WO_4 + xH_2O_2 \xrightarrow{\text{heating}} WO_3 \cdot xH_2O_2 \cdot H_2O$$
 (2)

 $WO_3 \cdot xH_2O_2 \cdot H_2O$

$$\xrightarrow{\text{Pt surface}} WO_3(\text{layer}) + 2(x+1)H_2O + O_2(g)$$
 (3)

Following eq 2, the tungstic acid and H2O2 are converted to a WO₃ precursor containing peroxide and water (peroxopolytungstic acid). The peroxide-containing complex is subsequently converted to (supported) WO₃ crystals and oxygen (eq 3), presumably catalyzed by the Pt surface. The differences in adhesion, crystal orientation, and morphology of WO3 on Pt relate to the applied H₂O₂ concentration in the precursor solution. In high concentrations of H2O2, Pt catalyzes decomposition of H2O2, which is in competition with decomposition of the peroxopolytungstic acid intermediate. H₂O₂ decomposition leads to extensive formation of O₂ bubbles, inhibiting decomposition of peroxopolytungstic acid at the Pt substrate. Presumably, WO3 crystals grow extensively in solution and subsequently deposit on the substrate, which affects WO₃ adhesion and yields the obtained highly porous morphology. A schematic overview of the two proposed mechanisms for growth is provided in Figure 3.

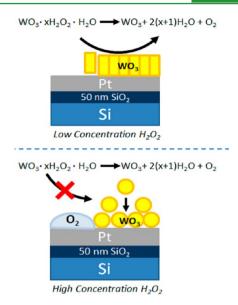


Figure 3. Schematic overview of the two proposed growth mechanisms for WO $_3$ at Pt surfaces in the presence of low and high concentrations of H_2O_2 , respectively. In the presence of high concentrations of H_2O_2 , oxygen bubbles are formed, resulting in a porous (flower-type) WO $_3$ layer loosely attached to the Pt layer. For low concentrations of H_2O_2 , peroxopolytungstic acid decomposes on the Pt surface, and a strongly adhering WO $_3$ layer is formed.

To evaluate the proposed catalytic effect of Pt in peroxopolytungstic acid decomposition, preferential growth of WO3 on Pt was attempted, as was previously reported for ZnO nanostructures on gold nanoparticles. 18-20 To this end, a Pt pattern of 10 and 50 μ m sized dots was prepared on a Si/SiO₂/ Ti substrate by microlithography. After application of the hydrothermal growth procedure with a relatively low concentration of H₂O₂, the formation of WO₃ was analyzed by SEM in combination with EDX. The results are shown in Figure 4. SEM images with representative EDX maps are shown for the 50 µm dots (Figure 4a,b) and the 10 µm dots (Figure 4c,d), respectively. The SEM images confirm the preferential growth of WO₃ crystals on the Pt dots. Mapping of the specific elements, i.e., Si (red), Pt (magenta), W (green), and O (blue), was performed using EDX. Between the dots, a dominant red color is visible and represents the Si substrate. On the dots, the main colors are green and blue, confirming the presence of W and O. Traces of the Pt substrate are visible in the 50 μ m dots, while the EDX result suggests the formation of a less dense WO_3 layer on the 10 μ m sized dots. Only a small part of the Pt film appears not to be covered by WO₃.

To analyze the properties of the interface of the Pt film and the deposited WO₃ crystals, photoelectrochemical characterization was performed, of which the results are shown in Figure 5. During the final annealing step, the thick layers with the flower-like morphology detached from the Pt surface because of low adhesion. Therefore, it was not possible to use these samples in the photoelectrochemical setup and measure the photocurrent. The cyclic voltammetry curves of the dense WO₃ layer are compared to the curves of the bare Pt layer (on the Si/SiO₂ substrate) in Figure 5a. In both cases, at an applied potential of 1.7 V versus reversible hydrogen electrode (RHE), the current is measured and assigned to electrolysis of H₂O. Oxygen is formed at the working electrode [the bare Pt substrate or the WO₃ layer (black curve in Figure 5a), respectively], while hydrogen is formed at the counter electrode

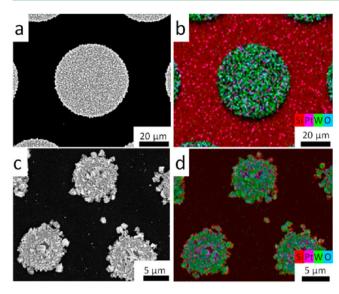


Figure 4. Images of WO₃ layers grown at patterned Pt surfaces on Si, obtained by SEM combined with elemental mapping by EDX. (a) SEM images of $50-\mu$ m-diameter Pt/WO₃ dots and (b) the corresponding EDX map of Si, Pt, W, and O. (c) SEM images of $10-\mu$ m-diameter Pt/WO₃ dots and (d) the corresponding EDX map of Si, Pt, W, and O.

(a Pt mesh). This is confirmed by the electrochemical water-splitting potential of 1.73 V typically obtained with two Pt electrodes, being the result of a theoretical value of 1.23 V, and a 0.5 V overpotential for water oxidation. When a 1.5 AM solar simulator is used to illuminate the substrates, the bare Pt film does not show a photoresponse, as expected. On the other hand, for the WO_3 layer, a clear photoresponse is measured. The onset potential where oxygen evolution is initiated has decreased from 1.7 to 0.75 V vs RHE, which indicates a shift of 0.95 V by illumination of WO_3 . The photocurrent obtained at a bias potential of 1.23 V is about 1.1 mA/cm².

To further characterize the response of the system, a chronoamperometry measurement was performed; see Figure 5b. The sample was intermittently exposed to light in periods of 30 s at a bias potential of 1.23 V vs RHE. When the sample was illuminated, a photocurrent of about 1.1 mA/cm² was measured, in agreement with the curve of Figure 5a. The photoresponse was relatively independent of the number of light exposure cycles, demonstrating the reproducibility of the photoresponse and high stability of the WO $_3$ layer.

According to the Shockley-Queisser limit, the maximum achievable photocurrent at 1.5 AM solar irradiation for WO_3 (2.6 eV band gap) is 6.0 mA/cm². The 1.1 mA/cm² value is thus 18.3% of the maximum achievable photocurrent. In the literature, a range of photocurrents are reported for supported WO3 layers, typically obtained with different light sources. For example, a high photocurrent of 2.6 mA/cm² was reported for nitrogen-doped WO3, but this was achieved with a 500 W xenon lamp emitting light of high intensity.²³ Photocurrents measured with a 1.5 AM solar simulator are included in Table 1 for comparison. The photocurrents in the table are the values at 1.23 V vs RHE. With the Nernst equation, the potentials were corrected for differences in the pH and the reference electrode used. Compared to other hydrothermally grown layers, our WO₃ layers at Pt substrates show a significantly higher photocurrent. This confirms the favorable electron transfer of photoexcited WO3 to the Pt film and is in agreement with a

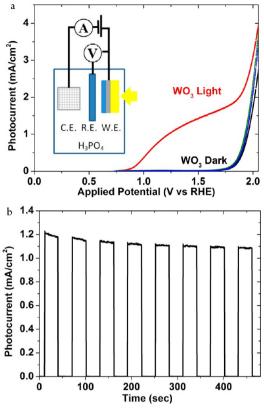


Figure 5. Photocurrent measurements of the WO $_3$ layer (grown in relatively low concentrations of H_2O_2) in a 0.3M H_3PO_4 electrolyte. A scan rate of 50 mV/s was applied. (a) $I\!-\!V$ curves of the Si/Pt substrate (dark is the blue line; light is the green line) and a Si/Pt/WO $_3$ sample (dark is the black line; light is the red line). Clearly, the photocurrent is measured for the WO $_3$ layer, when exposed to light. The inset shows the measurement configuration used for the measurements. (b) Chronoamperometry measurement of the WO $_3$ layer. The applied bias was 1.23 V vs RHE. A clear change in the photocurrent between light on and off is measured.

high electron conductivity. The photocurrent of 1.1 mA/cm² is lower than the photocurrent reported by Hong et al. This might be related to the thickness of the WO₃ layer (3.3 μ m, prepared by polymer-assisted deposition in the study of Hong et al., vs 0.5 μ m in the present study), as well as to the high crystallinity of the layers prepared by Hong et al. ²⁶ The onset potentials obtained with our layers showed values comparable to those reported for conductive glass substrates, so the Schottky barrier between WO₃ and Pt, if unfavorable, does not appear to significantly inhibit electron transfer.

CONCLUSION

We demonstrate that by use of a hydrothermal method growth of WO $_3$ in intimate contact with a Pt film can be achieved. The growth is likely controlled by the Pt-catalyzed decomposition of a peroxopolytungstic acid intermediate, as confirmed by the spatial distribution achieved using Si surfaces equipped with Pt dots. A tungsten oxide hydrate phase is thus formed, which is converted upon annealing to a monoclinic WO $_3$ phase. The Pt-supported layers show a significant photoresponse of 1.1 mA/cm² at a bias potential of 1.23 V vs RHE. This response is significantly higher than most previously reported values for hydrothermally grown layers on ITO and FTO glass. This is highly relevant for the creation of new devices for photo-

Table 1. Selected Literature Overview of Photocurrents Obtained for WO₃ Layers Using a 1.5 AM Solar Simulator

material system	growth method	electrolyte	photocurrent [mA/cm ²]	onset [V vs RHE]	reference
WO ₃ at Pt	hydrothermal growth	0.3 M H ₃ PO ₄	1.1	0.75	this work
WO ₃ at SnO ₂ :F-coated glass	hydrothermal growth	$0.5 \text{ M H}_2\text{SO}_4$	0.6	0.45	Hong et al. ²⁴
WO ₃ at SnO ₂ :F-coated glass	hydrothermal growth	$1 \text{ M H}_2\text{SO}_4$	0.4	0.55	Jiao et al. ¹³
WO ₃ at SnO ₂ :F-coated glass	reacting RF magnetron sputtering	$0.33 \text{ M H}_3\text{PO}_4$	1.1	0.95	Marsen et al. ²⁵
WO ₃ at SnO ₂ :F-coated glass	polymer-assisted deposition	$0.5 \text{ M H}_2\text{SO}_4$	2.3	0.60	Hong et al. ²⁶
WO ₃ at SnO ₂ :F-coated glass	chemical solution deposition	1 M HClO ₄	2.3	0.45	Santato et al. ²⁷

electrochemical production of hydrogen. Future studies will involve the use of other metal films and study of the effect of the composition of such a film on formation of the WO₃ layer, as well as on the achievable photocurrents. Further, the patterned surfaces might find application in advanced sensing and photoelectrochemical devices, requiring efficient metal—semiconductor interfaces.

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Notes

The authors declare no competing financial interest.

■ ACKNOWLEDGMENTS

This work was supported by the Strategic Research Orientation "Nanomaterials for Energy", MESA + Institute for Nanotechnology, University of Twente, Twente, The Netherlands. W.G.v.d.W. acknowledges financial support from the European Research Council (ERC Starting Grant 240433). We acknowledge Mark Smithers and Johnny Sanderink for the SEM images and Saurabh Bose for assistance in the ion etching of Pt.

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